Substitute Form PTO-1449 (Modified)

U.S. Department of Commerce Patent and Trademack Office Attorney's Docket No. 10559-895001

Application No. 10/799,928

Information Disclosure Statement by Applicant

(Use several sheets if necessary) AUG U 8 2006

Applicant Alexander Tregub et al.

Filing Date
March 12, 2004

Group Art Unit

(37 CFR §1.98(b))

**SAP**Hent Documents Document **Publication** Examiner Desig. Filing Date Initial ID Number Date Patentee Class **Subclass** If Appropriate NN 2001/0004508 06/2001 Shirasaki AA 08/2001 AB 2001/0014375 Tanaka Tsumoto et al. AC 2002/0136965 09/2002 AD 2002/0179852 12/2002 Zheng et al. 05/2003 Fujita et al. AE 2003/0096178 AF 2003/0187168 10/2003 Sunaga et al. AG 2003/0192567 10/2003 Koizumi et al. AH 2004/0123950 07/2004 Bovd 2005/0045262 03/2005 Eschbach et al. ΑI 03/2005 ΑJ 2005/0048376 Eschbach et al. 2005/0203254 ΑK 09/2005 Tregub et al. AL 4,060,654 11/1977 Ouenneville 4,737,387 Yen AM 04/1988 01/1995 Hamada et al. AN 5,378,514 5,643,654 07/1997 AO Fujita et al. Hamada et al. AP 5,693,382 12/1997 03/1998 AQ 5,723,860 Hamada et al. 04/2000 AR 6,055,040 Sego 6,083,577 07/2000 Nakagawa et al. AS Shirota et al. AT 6.111,062 08/2000 AU 6,300,019 10/2001 Ikeda et al. ΑV 6,436,586 08/2002 Matsuoka et al. AW 6,524,754 02/2003 Eynon 04/2003 Matsukura et al. AX 6,548,129 AY 6,639,650 10/2003 Shirasaki ΑZ 6,652,958 11/2003 Tobita NN BA 6,822,731 11/2004 Laganza et al.

Examiner	Signat	ure	
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/Nathan Nutter/ (12/08/2006)

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	losure Statement plicant	Applicant Alexander Tregub et al.	
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NN	ВТ	Shu, et al., "Hard Pellicle Study for 157-nm Lithography", Preprint, to appear in the Proceedings of Photomask Japan, pp. 1-12 (2002).
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Sheet 1 of 1

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	AN								
	AO								
	AP		·						

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	AS				
	AT				

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